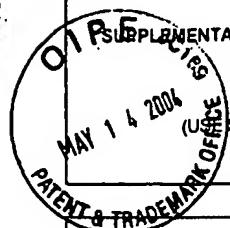


FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. IMEC283.001AUS	APPLICATION NO. 10/863,340
<p>ON 1 SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(USE SEVERAL SHEETS IF NECESSARY)</p>		APPLICANT Rottenberg, et al.	
		FILING DATE September 15, 2003	GROUP 2818



U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
<i>John</i>	1	4,211,488	07/08/80	Kleinknecht			
	2	6,323,951 B1	11/27/01	Borden, et al.			
	3	2002/0027660 A1	03/07/02	Borden, et al.			
	4	2002/0085211 A1	07/04/02	Borden, et al.			
<i>John</i>	5	2003/0043382 A1	03/06/03	Borden, et al.			

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	6	Sydot, et al., "Differential photoreflectance from modulation-doped heterojunctions", Applied Physics Letters, vol. 58, no. 9, pp. 948-950, (1991)
<i>John</i>	7	International Search report dated March 24, 2004, for European Application No. 03 44 7186.

EXAMINER <i>John</i>	DATE CONSIDERED <i>05/04/05</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMITY WITH MPEP 809; DRAW LINE THROUGH CITATION IF NOT IN CONFORMITY AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	

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O P R E J O DEE 12 2003 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Rottenburg, et al.	
		FILING DATE September 15, 2003	GROUP 2818

FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
dhm	1. WO 02/01584 A1	01/03/02	PCT			X	

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)						
dhm	2. Muldavin, et al., "High-isolation CPW MEMS shunt switches-Part 1: Modeling", IEEE Transactions on Microwave Theory and Techniques, vol. 48, no. 6, pp. 1045-1052, (June 2000).						
	3. Nguyen, et al., "Micromachined devices for wireless communications", Proceedings of IEEE, vol. 86, no. 8, pp. 1756-1768, (August 1998)						
	4. Rebeiz, et al., "RF MEMS switches and switch circuits", IEEE Microwave Magazine, pp. 59-71, (December 2001).						
	5. Tilmans, et al., "Wafer-level packaged RF-MEMS switches fabricated in a CMOS fab", IEEE, pp. 921-924, (2001).						
	6. Yao, et al., "Micromachined low-loss microwave switches", IEEE Journal of Microelectromechanical Systems, vol. 8, no. 2, (June 1999).						
dhm	7. Yao, J. Jason, "Topical Review: RF MEMS from a device perspective", J. Micromech. Microeng., vol. 10, pp. R9-R38, (2000).						

EXAMINER	<i>Thao</i>	DATE CONSIDERED	<i>05/09/05</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.			